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## An Ultrasensitive Strain Sensor with Large Strain Range Based on Graphene Armour Scales

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## Supplementary Information

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Figure S1 The absolute resistance change versus strain and the initial resistance of the sensor before producing the armour scales.

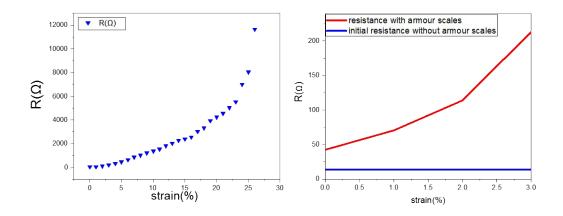


Figure S2 The 5000 cycles test and zoom-in view of the relative resistance change under the strain of 13% of the sensor.

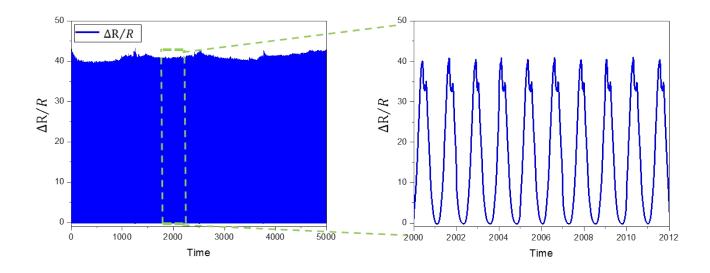


Figure S3 The sample to sample variation of this sensor.

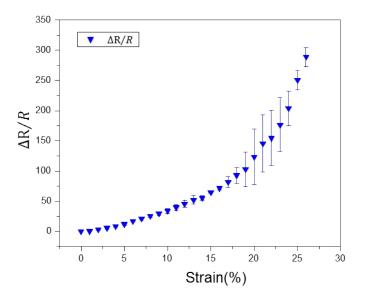


Figure S4 The hysteretic property of the sensor.

